



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Christian Petersen, et al.	Examiner:	Russell Marc Kobert
Serial No.:	10/675886	Group Art Unit:	2829
Filed:	September 30, 2003	Docket No.:	00900.0302-US-C1
Title:	MULTI-POINT PROBE		

CERTIFICATE UNDER 37 C.F.R. 1.8: The undersigned hereby certifies that this document is being deposited in the United States Postal Service, as first class mail, with sufficient postage, in an envelope addressed to: Mail Stop RCE, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on April 28, 2006.

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Michele A. Read  
Name

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*Michele A. Read*  
Signature

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**  
**UNDER 37 C.F.R. §1.97(b)**

Mail Stop RCE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Applicants respectfully submit the items of information on the enclosed Form 1449 for the attention of the Examiner in the above-identified application.

This Information Disclosure Statement is being filed within three months of the filing of a national application other than a continued prosecution application under 37 C.F.R. 1.53(d); within three months of the date of entry of the national stage as set forth in 37 C.F.R. 1.491 in an international application; before the mailing date of a first Office Action on the merits, or before the mailing of a first Office Action after the filing of a request for continued examination under 37 C.F.R. 1.114. Accordingly, no fee is due for consideration of the items listed on the enclosed Form 1449.

A copy of each document or other information listed on the enclosed Form 1449 is enclosed in accordance with 37 C.F.R. §1.98(a)(2). Copies of references B-D, F-K, and N were cited in an International Search Report in a corresponding PCT application. A copy of the International Search Report is enclosed. While References D (DE 43 01 420), G (JP 8-15318), and H (DE 196 48 475) are in a foreign language,

according to MPEP §609 A(3), "Where the information listed is not listed in the English language, but was cited in a search report of other action...the requirement for a concise explanation of relevance can be satisfied by submitting an English-language version of the search report..." Therefore, Applicants believe they have fulfilled the obligation to provide English language versions of DE 43 01 420, JP 8-15318, and DE 196 48 475.

No representation is made that a reference is "prior art" within the meaning of 35 U.S.C. §§102 and 103. In addition, Applicants do not represent that a reference has been thoroughly reviewed or that any relevance of any portion of a reference is intended, and reserve the right to establish otherwise under 37 C.F.R. §1.131 or others.

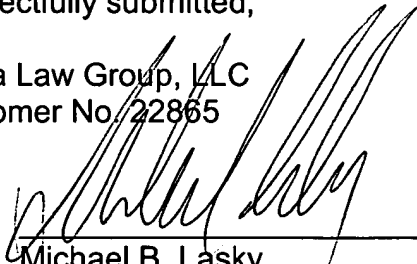
Consideration of the items listed is respectfully requested. According to M.P.E.P. §609, Applicants request that the Examiner return a copy of the attached Form 1449, marked as being considered and initialed by the Examiner, to the undersigned with the next official communication.

Authorization is hereby given to charge any additional fees or credit any overpayments that may be deemed necessary to Deposit Account Number 50-1038.

Respectfully submitted,

Altera Law Group, LLC  
Customer No. 22865

Date: April 28, 2006

By:   
Michael B. Lasky  
Reg. No. 29,555  
MBL/mar



## INFORMATION DISCLOSURE STATEMENT

PTO Form 1449

Docket Number  
00900.0302-US-C1Serial Number  
10/675886Applicant(s)  
Christian Petersen, et al.Filing Date  
September 30, 2003Group Art Unit  
2829

## U.S. PATENT DOCUMENTS

EXAMINER INITIALS	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB-CLASS	FILING DATE (IF APPROPRIATE)

## FOREIGN PATENT DOCUMENTS

EXAMINER INITIALS	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION	
							YES	NO
	A	EP 0 299 875	01/18/89	European Patent Office				
	B	01147374	06/09/89	Japan			Abstract	
	C	EP 0 466 274	01/15/92	European Patent Office				
	D	DE 43 01 420	06/24/93	Germany				
	E	WO 94/11745	05/26/94	WIPO				
	F	07199219	08/04/95	Japan			Abstract	
	G	8-15318	01/19/96	Japan				
	H	DE 196 48 475	06/05/97	Germany				
	I	EP 0 899 538	03/03/99	European Patent Office				

## OTHER DOCUMENTS

	J	Fujii, et al., "Micropattern measurement with an atomic force microscope", <u>Journal of Vacuum Science &amp; Technology: Part B</u> , Vol. 9, No. 2, pp. 666-669 (March/April 1991).
	K	Hong, et al., "Design and Fabrication of a Monolithic High-Density Probe Card for High-Frequency On-Water Testing", <u>Institute of Electrical and Electronics Engineers</u> , pp. 289-292 (December 3, 1989).
	L	Koops, et al., "Constructive three-dimensional lithography with electron-beam induced deposition for quantum effect devices", <u>Journal of Vacuum Science &amp; Technology B (Microelectronics Processing and Phenomena)</u> , Vol. 11, No. 6, pp. 2286-2289 (November/December 1993).
	M	Koops, et al., "Conductive dots, wires, and supertips for field electron emitters produced by electron-beam induced deposition on samples having increased temperature", <u>Journal of Vacuum Science &amp; Technology B (Microelectronics Processing and Phenomena)</u> , Vol. 14, No. 6, pp. 4105-4109 (November/December 1996).
	N	Lee, et al., "High-Density Silicon Microprobe Arrays for LCD Pixel Inspection", <u>Institute of Electrical and Electronics Engineers</u> , pp. 429-434 (February 11, 1996).
	O	Niu, et al., "Double-tip scanning tunneling microscope for surface analysis", <u>Physical Review B</u> , Vol. 51, No. 8, pp. 5502-5505 (February 15, 1995).
	P	Shi, et al., "New method of calculating the correction factors for the measurement of sheet resistivity of a square sample with a square four-point probe", <u>Rev. Sci. Instrum.</u> , Vol. 68, No. 4, pp. 1814-1817 (April 1997).
	Q	Smits, "Measurement of Sheet Resistivities with the Four-Point Probe", <u>The Bell System Technical Journal</u> , Vol. 37, pp. 711-718 (May 1958).

Examiner:

Date Considered: